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Substitute for form 1449B/PTO Complete if Known **Application Number** Unassign (d) 02/02/2005 INFORMATION DISCLOSURE STATEMENT BY APPLICANT Filing Date First Named Inventor Tadahiro OHMI Date Submitted: August 8, 2006 Group Art Unit Unassigned (use as many sheets as necessary) **Examiner Name** Unassigned Attorney Docket Number 039262-0156 Sheet 1

U.S. PATENT DOCUMENTS							
Examiner Initials*	Cite No.1	U.S. Patent Document			Date of Publication of	Pages, Columns, Lines, Where Relevant	
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ALL REFERENCES CONSIDERED EXCEPT WHERE LINED THROUGH. /C.E./

Examine Signature	/Caridad Everhart/	Date Considered	04/08/2008

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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